Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

Claim 1 (currently amended): A probe card assembly for electrically communicating test data between a semiconductor test tester apparatus and a semiconductor device under test, said probe card assembly comprising:

a substrate configured to electrically contact said semiconductor tester apparatus,

a plurality of probes configured to electrically contact said semiconductor device under lest, said plurality of probes located to a first side of said substrate, and

a daughter card <u>secured located</u> to a second side of said substrate in <u>spaced relationship to</u> said substrate, said daughter card being substantially coplanar to said substrate, there being a <u>space between said daughter card and said substrate</u>.

Claim 2 (original): The probe card assembly of claim 1 further comprising an electric circuit at least a portion of which is disposed on said daughter card.

Claim 3 (original): The probe card assembly of claim 2, wherein said electric circuit includes active circuit elements.

Claim 4 (original): The probe card assembly of claim 2, wherein said electric circuit is configured to enhance test capabilities of said semiconductor test apparatus.

Claim 5 (original): The probe card assembly of claim 2, wherein said electric circuit is configured to customize at least a portion of said test data to test needs of said semiconductor device under test.

Claim 6 (original): The probe card assembly of claim 5, wherein said test data comprises test signals generated by said semiconductor test apparatus and said electric circuit customizes at least a portion of said test signals.

Claim 7 (original): The probe card assembly of claim 5, wherein said test data comprises response signals generated by said semiconductor device under test and said electric circuit customizes at least a portion of said response signals.

Claim 8 (original): The probe card assembly of claim 1 further comprising a plurality of said daughter cards.

Claim 9 (original): The probe card assembly of claim 8, wherein said plurality of daughter cards are disposed in stacked relationship to each other.



Claim 10 (original): The probe card assembly of claim 8 further comprising an electric circuit at least a portion of which is disposed on each of said plurality of daughter cards.

Claim 11 (original): The probe card assembly of claim 10, wherein said electric circuit includes active circuit elements.

Claim 12 (original): The probe card assembly of claim 10, wherein said electric circuit is configured to enhance test capabilities of said semiconductor test apparatus.

Claim 13 (original): The probe card assembly of claim 10, wherein said electric circuit is configured to customize at least a portion of said test data to test needs of said semiconductor device under test.

Claim 14 (original): The probe card assembly of claim 13, wherein said test data comprises test signals generated by said semiconductor test apparatus and said electric circuit customizes at least a portion of said test signals.

Claim 15 (original): The probe card assembly of claim 13, wherein said test data comprises response signals generated by said semiconductor device under test and said electric circuit customizes at least a portion of said response signals.

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Claim 16 (original): The probe card assembly of claim 8, wherein said plurality of daughter cards includes at least three daughter cards.

Claim 17 (original): The probe card assembly of claim 16 further comprising an electric circuit at least a portion of which is disposed on each of said at least three daughter cards.

Claim 18 (original): The probe card assembly of claim 16, wherein said at least three daughter cards are disposed in stacked relationship to each other.

Claim 19 (currently amended): A method of making a probe card assembly, said method comprising:

providing a substrate including a plurality of tester contacts,

securing disposing a plurality of probes to a first side of said substrate, said probes configured to electrically contact a semiconductor device under test, and

securing disposing a daughter card to a second side of said substrate in spaced relationship to said substrate, said daughter card being substantially coplanar to said substrate, there being a space between said daughter card and said substrate.

Claim 20 (original): The method of claim 19 further comprising:

providing an electric circuit, and

disposing at least a portion of said electric circuit on said daughter card.

Claim 21 (original): The method of claim 20, wherein said electric circuit includes active circuit elements.

Claim 22 (original): The method of claim 20, wherein said electric circuit is configured to enhance test capabilities of said semiconductor test apparatus.

Claim 23 (original): The method of claim 20, wherein said electric circuit is configured to customize test data to test needs of said semiconductor device under test.



Claim 24 (original): The method of claim 23, wherein said test data comprises test signals to be input into said semiconductor device under test and said electric circuit customizes at least a portion of said test signals.

Claim 25 (original): The method of claim 23, wherein said test data comprises response signals generated by said semiconductor device under test and said electric circuit customizes at least a portion of said response signals.

Claim 26 (original): The method of claim 19 further comprising securing a plurality of said daughter cards to said substrate.

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Claim 27 (original): The method of claim 26 further comprising securing said plurality of daughter cards to said substrate in stacked relationship to each other.

Claim 28 (original): The method of claim 26 further comprising:

providing an electric circuit, and

disposing at least a portion of said electric circuit on each of said plurality of daughter cards.

Claim 29 (original): The method of claim 28, wherein said electric circuit includes active circuit elements.

Claim 30 (original): The method of claim 28, wherein said electric circuit is configured to enhance test capabilities of said semiconductor test apparatus.

Claim 31 (original): The method of claim 28, wherein said electric circuit is configured to customize test data to test needs of said semiconductor device under test.

Claim 32 (original): The method of claim 31, wherein said test data comprises test signals to be input into said semiconductor device under test and said electric circuit customizes at least a portion of said test signals.

Claim 33 (original): The method of claim 31, wherein said test data comprises response signals generated by said semiconductor device under test and said electric circuit customizes at least a portion of said response signals.

Claim 34 (original): The method of claim 26, wherein said plurality of daughter cards includes at least three daughter cards.

Claim 35 (original): The method of claim 34 further comprising:

providing an electric circuit, and

disposing at least a portion of said electric circuit on each of said at least three daughter cards.

Claim 36 (original): The method of claim 34 further comprising securing each of said at least three daughter cards to said substrate in stacked relationship to each other.

Claim 37 (original): A probe card assembly made using the process of claim 19.

Claim 38 (original): A probe card assembly made using the process of claim 20.

Claim 39 (original): A probe card assembly made using the process of claim 22.

Claim 40 (original): A probe card assembly made using the process of claim 26.

Claim 41 (original): A probe card assembly made using the process of claim 30.

Claim 42 (currently amended): A probe card assembly comprising:

printed circuit means for electrically communicating with a semiconductor tester apparatus,

contact means for electrically communicating with a semiconductor device under test, said contact means being secured to a first surface of said printed circuit means, and

daughter card means for physically supporting at least a portion of an electric circuit, said daughter card means secured to a second surface of said printed circuit means and being substantially coplanar to said printed circuit means, and

an electric circuit, at least a portion of which is disposed on said daughter card means.



Claim 43 (original): The probe card assembly of claim 42, wherein said daughter card means comprises a plurality of daughter cards in stacked relationship to each other, each of said plurality of daughter cards being substantially coplanar to said printed circuit means.

Claim 44 (original): The probe card assembly of claim 43, wherein said plurality of daughter cards includes at least three daughter cards.

Claim 45 (original): The probe card assembly of claim 42, wherein said electric circuit comprises processing means for processing test data for testing said semiconductor device under test.

Claim 46 (original): The probe card assembly of claim 45, wherein said processing means enhances test capabilities of said semiconductor test apparatus.

Claim 47 (original): The probe card assembly of claim 45, wherein said processing means customizes said test data to meet test needs of said semiconductor device under test.

Claim 48 (original): The probe card assembly of claim 47, wherein said test data comprises test signals to be input into said semiconductor device under test and said processing means customizes at least a portion of said test signals.

Claim 49 (original): The probe card assembly of claim 47, wherein said test data comprises response signals generated by said semiconductor device under test and said processing means customizes at least a portion of said response signals.

Claim 50 (original): A probe card assembly for electrically communicating test data between a semiconductor test apparatus and a semiconductor device under test, said probe card assembly comprising:

a printed circuit board configured to electrically contact said semiconductor tester apparatus,

a plurality of probes configured to electrically contact said semiconductor device,

a daughter card secured to said printed circuit board in spaced relationship to said printed circuit board, said daughter card being substantially coplanar to said printed circuit board, and

an electric circuit configured to enhance test capabilities of said semiconductor test apparatus, at least a portion of said electric circuit being disposed on said daughter card.

Claim 51 (original): The probe card assembly of claim 50 further comprising a plurality of said daughter cards.

Claim 52 (original): The probe card assembly of claim 51, wherein said daughter cards are disposed in stacked relationship to each other.

Claim 53 (original): The probe card assembly of claim 51, wherein said plurality of daughter cards includes at least two daughter cards.

Claim 54 (original): The probe card assembly of claim 51, wherein said plurality of daughter cards includes at least three daughter cards.

Claim 55 (original): The probe card assembly of claim 50, wherein said electric circuit enhances test capabilities of said semiconductor test apparatus by processing at least a portion of said test data.

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Claim 56 (original): The probe card assembly of claim 55, wherein said test data comprises test signals generated by said semiconductor tester apparatus and said electric circuit processes at least a portion of said test signals.

Claim 57 (original): The probe card assembly of claim 55, wherein said test data comprises response signals generated by said semiconductor device and said electric circuit processes at least a portion of said response signals.